AMENDMENTS TO THE CLAIMS

1. (Currently Amended) A method of forming a liquid crystal layer on a substrate having a sealed pattern, comprising:

preparing a liquid crystal material in a projecting portion-having a nozzle plate containing a plurality of orifices;

applying a vibration an on voltage to a resonator during emitting of the liquid crystal material to generate a vibration so as to apply and pressure to the projecting portion so as to emit the liquid crystal material from the projecting portion simultaneously from the plurality of orifices, said vibration being generated from a resonator overlapping the plurality of orifices;

moving the substrate in one direction; and

depositing the liquid crystal material emitted simultaneously from the plurality of orifices from the projecting portion uniformly onto the substrate during the movement moving of the substrate in the one direction and applying a voltage to the projecting portion to adjust the volume of the emitted liquid crystal material according to a position of the moving substrate.

2. (Currently Amended) The method according to claim 1, wherein the projecting portion has a nozzle plate containing a plurality of orifices, said the nozzle plate adjusts adjusting the applied pressure for emitting the liquid crystal material, the liquid crystal material being emitted through the plurality of orifices.

3. (Cancelled)

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4. (Original) The method according to claim 1, wherein the liquid crystal material is

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emitted and deposited in a vacuum chamber.

5. (Cancelled)

6. (Currently Amended) The method according to elaim 5 claim 1, wherein the generated

vibration is transmitted to the projecting portion through a resonating plate.

7. (Original) The method according to claim 1, wherein the substrate has a black matrix

under the sealed pattern.

8. (Original) The method according to claim 7, wherein the liquid crystal material start

and stop is deposited on the black matrix.

9. (Currently Amended) An apparatus for forming a liquid crystal layer on a substrate

having a seal pattern, comprising:

a projecting portion having a nozzle plate containing a plurality of orifices

simultaneously for emitting a liquid crystal material;

a resonator overlapping the plurality of orifices for generating a vibration upon

application of an on voltage to the resonator during emitting of the liquid crystal material;

a resonating plate located between the resonator and the projecting portion for

transmitting the vibration to the projecting portion; and

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a stage for moving the substrate in one direction during continuously emitting of the

liquid crystal material simultaneously from the projecting portion uniformly onto the substrate

wherein a voltage is applied to the resonator to adjust the volume of the emitted liquid crystal

material and according to a position of the moving substrate.

10. (Currently Amended) The apparatus according to claim 9, wherein the projecting

portion has a nozzle plate containing a plurality of orifices, the nozzle plate adjusts adjusting the

applied pressure for emitting the liquid crystal material, the liquid crystal material being emitted

through the plurality of orifices.

11. (Cancelled)

12. (Currently Amended) The apparatus according to claim 9, wherein means are is

provided for moving the stage.

13. (Original) The apparatus according to claim 9, further comprising a vacuum chamber

for encompassing the projecting portion, the resonator and the resonating plate.

14. (Currently Amended) The apparatus according to claim 9, wherein voltage means are

is provided for generating vibration in the resonator.

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15. (Currently Amended) The method according to claim 1, wherein an on-off of a the on

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voltage is adjusted applied according to a position of the moving substrate.

16. (Currently Amended) The apparatus of claim 9, wherein means are is provided for

adjusting an on-off of applying the on voltage according to a position of the moving substrate.